# LabAdviser update: 17/1 2020

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| Updated Subject | Contributor | Link to the updated pages |
| **PECVD4 Nitride stress tests** | **Dennis Høj @Fysik** | [Deposition\_of\_Silicon\_Nitride\_using\_PECVD/MF\_SiN\_results](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Nitride/Deposition_of_Silicon_Nitride_using_PECVD/MF_SiN_results) |
| **New Stylus profiler**  New stylus profiler: Dektak150 positioned in building 347-183 | **Karen Birkelund @Nanolab** | [Characterization/Profiler#Stylus\_Profiler:\_Dektak150](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/Profiler#Stylus_Profiler:_Dektak150) |
| **Descum in the plasma ashers** | **Jitka Urbankova @Nanolab** | [Lithography/Descum](http://labadviser.nanolab.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/Descum) |

# Equipment Manuals updated in LabManager (since 16th of December):

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

5. 3. 6.19) Manual for Stylus profiler: Dektak 150, ver 15. Udstyrskontrol, 5. 3. 6 Backend, PM-III, 13.01.2020

5. 3. 7.42) Manual for Nikon ECLIPSE L200 (2) optical microscope, ver 2.35. Udstyrskontrol, 5. 3. 7 Characterization, PM-III, 13.01.2020

5. 3. 7.11) Manual for Nikon ECLIPSE L200 optical microscope, ver 5.35. Udstyrskontrol, 5. 3. 7 Characterization, PM-III, 13.01.2020

5. 3. 7.47) Manual for AFM Icon-PT 1 & 2, ver 4.15. Udstyrskontrol, 5. 3. 7 Characterization, PM-III, 07.01.2020

5. 3. 6.00) Manual for TPT wire bonder, ver 45. Udstyrskontrol, 5. 3. 6 Backend, PM-III, 13.01.2020

5. 3. 5.11) Manual for RTP Jipelec, ver 75. Udstyrskontrol, 5. 3. 5 Thermal Process, PM-III, 13.01.2020

5. 3. 1.54) DUV STEPPER job file creation manual, ver 25. Udstyrskontrol, 5. 3. 1 Photolithography, PM-III, 20.12.2019

5. 3. 2.08) Manual for PECVD3, ver 1.75. Udstyrskontrol, 5. 3. 2 Thin Film Deposition, PM-III, 13.01.2020

5. 3. 7.32) Manual for Leitz Medilux optical microscope, ver 2.25. Udstyrskontrol, 5. 3. 7 Characterization, PM-III, 13.01.2020 5. 3. 7.33) Manual for Leica S8 APO optical microscope, ver 2.25. Udstyrskontrol, 5. 3. 7 Characterization, PM-III, 13.01.2020

5. 3. 7.35) Manual for Zeiss Jenatech (particle measturements) optical microscope, ver 2.25. Udstyrskontrol, 5. 3. 7 Characterization, PM-III, 13.01.2020

5. 3. 7.40) Manual for Nikon ME 600 optical microscope, ver 2.25. Udstyrskontrol, 5. 3. 7 Characterization, PM-III, 13.01.2020